ABSTRACT

In a microwave plasma processing apparatus, a shower plate or plasma transmission window facing a substrate to be processed is formed to have a concaved surface at a side facing the substrate to be processes for compensating for a decrease of plasma density in the peripheral region of the substrate to be processed. As a result, stable and uniform plasma is maintained in the vicinity of the surface of the substrate to be processed even in the case a low pressure plasma process such as etching is conducted. Further, such a construction facilitates plasma ignition.



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